



on an iterative stochastic approximation technique.<sup>4,5</sup> On iteration  $(n + 1)$  the control voltages  $u_j^{(n+1)}$  applied to  $N$  wave-front corrector electrodes ( $j = 1, \dots, N$ ) are dependent on the product of applied random control-voltage perturbation values  $\{\delta u_j\}$  and the corresponding value  $\delta J^{(n)}$  of the measured system performance metric perturbation:  $u_j^{(n+1)} = u_j^{(n)} + \gamma \delta u_j^{(n)} \delta J^{(n)}$ . The value of the gain coefficient  $\gamma$  was controlled with an external (to the VLSI controller) supervisory system based on the use of a PC computer to increase the system convergence rate.<sup>6,7</sup>

For the system performance metric  $J$  we used the light power inside the 50- $\mu\text{m}$  pinhole (PH) placed in the lens focal plane and measured by a photomultiplier (PM). This metric  $J$  is proportional to the Strehl ratio,  $St$ , commonly used in adaptive optics. The values of performance metric  $J$  were used for on-chip computations of the control voltages  $\{u_i\}$  ( $i = 1, \dots, 132$ ). These control voltages were amplified by a set of high-voltage (HV) amplifiers (in the range 0 to 200 V) and applied to the micromirror-array electrodes.

The parallel analog on-chip control-voltage computations and the high (near 17-kHz) micromirror-array bandwidth allowed, for what is believed to be the first time, a submillisecond wave-front correction rate: The system performed 11,000 control-voltage updates (iterations) per second. The on-chip implementation of the stochastic parallel gradient-descent control technique for adaptive wave-front aberration compensation was first demonstrated in Ref. 8. A slower microscale (microelectromechanical system-VLSI) adaptive system with a  $6 \times 6$  micromirror array was recently reported in Ref. 7. The fast iteration rate achieved in the adaptive system reported here enabled us to demonstrate real-time adaptive correction of turbulence-induced wave-front phase distortions.

For evaluation of the dynamic wave-front aberration-correction efficiency a large ( $M = 2 \times 10^6$ ) set of performance metric values  $J^{(n)}$  ( $n = 1, \dots, M$ ) were measured at the adaptive-system iteration rate. The performance metric data were used for calculation of the probability density functions (PDFs)  $\rho(J)$  corresponding to different adaptation situations. The results are presented in Fig. 2 as normalized PDF curves. In the absence of adaptation (with both  $\mu\text{AOS}$  and TCS off) the PDF [curve (1)] is wide, indicating a high level of intensity scintillations. The compensation of wave-front tilts only [with the TCS on and the  $\mu\text{AOS}$  off, curve (3)] resulted in an increase of the averaged intensity level  $\langle J \rangle$  (a shift of the PDF curve maximum). Note that this compensation of just wave-front tilts had almost no effect on the intensity scintillation level. The PDFs without adaptation and with tilt-only compensation have approximately the same width (compare the corresponding curves in Fig. 2). This result can be explained by the presence of strong higher-order aberrations, resulting in the appearance of several spots in the focal intensity distribution. The TCS is not able to change the intensity distribution itself and instead moves the entire beam so that the most closely located intensity spot is placed inside the pinhole. Adaptive compensation for

high-order aberrations with the  $\mu\text{AOS}$  only [with the TCS off, curve (2)] resulted in a noticeable decrease of the intensity scintillation level (narrowing the PDF) compared with the PDF curves corresponding to the absence of adaptation or to the tilt-control PDF curve in Fig. 2. The high-order aberration compensation with the  $\mu\text{AOS}$  resulted in the formation of a single focal-plane spot, thus decreasing the intensity scintillation level. Compensation for both wave-front tilts and high-order aberrations [with both the TCS and the  $\mu\text{AOS}$  on, curve (4)] resulted in a further (approximately twofold) increase of the average metric value.

For comparison we also measured the PDF in the system without turbulence [curve (5) in Fig. 2], which corresponds to the optimal adaptation level that can be achieved. Note that this turbulence-free PDF curve is still quite wide (approximately half as wide as the corresponding curve with turbulence present). The intensity (metric) scintillations that cause the PDF curve widening in the absence of turbulence result from wave-front phase perturbations introduced by the  $\mu\text{AOS}$  itself. Indeed, in the absence of both turbulence and adaptation (no applied perturbations), the probability distribution curve (not shown in Fig. 2) is almost three times narrower than curve (5).

The frame-averaged focal-plane intensity distributions without correction and with adaptive compensation (with both the TCS and the  $\mu\text{AOS}$  on) are also shown in Fig. 2 as insets. For frame-averaging we used 50 intensity distributions taken in intervals of 1 s. The pinhole position is shown by the dotted circles, which correspond to a pinhole diameter of 50  $\mu\text{m}$ . Analysis of the experimental data shows that simultaneous correction of both

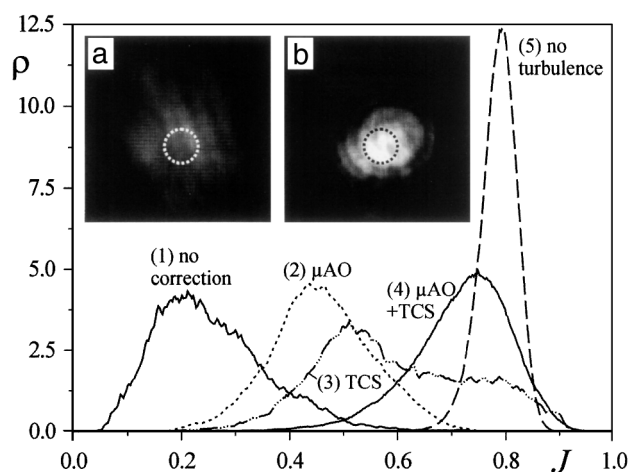


Fig. 2. PDFs,  $\rho$ , of metric values  $J$  (laser beam power inside the pinhole) and frame-averaged focal-plane intensity distributions (insets a and b) for [curves (1)–(4)] wave-front phase distortion correction in the presence of generated turbulence and [curve (5)] without turbulence. Curve (1), TCS and  $\mu\text{AOS}$  system off; curve (2), TCS off and  $\mu\text{AOS}$  on; curve (3), TCS on and  $\mu\text{AOS}$  off; curve (4) TCS and  $\mu\text{AOS}$  on; curve (5) TCS and  $\mu\text{AOS}$  on (no turbulence). The insets show the averaged focal-plane intensity distributions a, without and b, with wave-front distortion compensation. In b, both the TCS and the  $\mu\text{AOS}$  are on.

wave-front tilts and higher-order aberrations allowed nearly 92% of the maximum possible average metric value  $\langle J \rangle$  corresponding to undistorted conditions, to be achieved. The normalized standard deviation of the beam-quality metric  $\sigma_J$  was decreased from 0.41 for the uncorrected case to 0.13 when the TCS and  $\mu$ AOS were used simultaneously.

In conclusion, we have demonstrated real-time turbulence-induced wave-front phase distortion correction with a 134-control-channel adaptive-optics system consisting of a VLSI controller, a micromechanical mirror array, and a beam-steering system. Parallel analog control-voltage computation and the high bandwidth of the micromirror allowed an iteration rate of 11 kHz. The adaptive-optics system that was presented can be used for a variety of applications, for example, free-space laser communication and astronomical imaging.

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